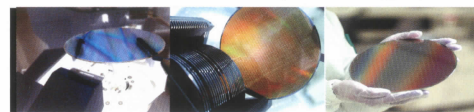


The Development and the commercialization of the Mask Aligner for wafer
Midas System will continue to grow along with the value creation for our customers.

<http://www.aligner.co.kr>

MDA-20000SA



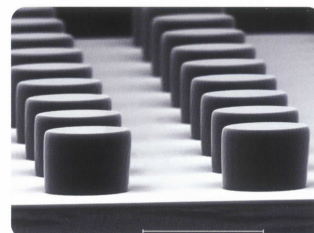
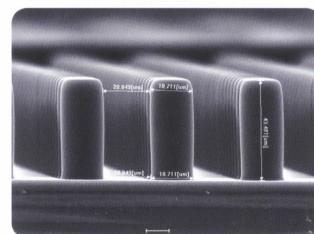
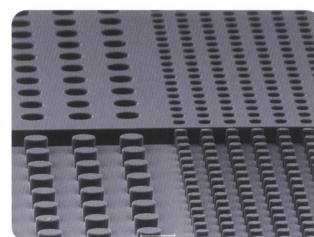
The MDA-20000SA is a brand new model of Full-field lithography systems. This brand new Semi Auto Aligner platform offers a higher Overlay Accuracy and more reliable operation.
The System can apply large area 20 inch substrates with UV Exposure.

The System is being successfully used in the Manufacturing of Flat panel devices, Touch Panel devices and other Technologies requiring fine geometry printing & precision Alignment.

This System has higher productivity and easy to control.



▼ SEM Image



ITEM	SPECIFICATIONS
Substrate Size	Customized (large area)
UV Lamp Power	5 kW
Resolution	down to 10um
Alignment Accuracy	±1 um
Lamp Uniformity	≤ ± 5%
Uniform Beam Size	24 × 24 inch
Beam Intensity	15~20mW/cm ² (Broad Band)
Exposure Time	0.1 to 999.9 sec
Motorized	Microscope X, Y -axis, Zoom and Focus Stage X, Y, θ and Z-axis
Process mode	Hard, Soft and Proximity



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